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CLAIM AMENDMENTS

The following is a complete listing of the pending claims:

 (Currently amended) A method of making a first-surface optical disk, comprising:

providing a father stamper, wherein the father stamper comprises spiral protrusions on a <u>first portion of a first surface corresponding to original laser cuts</u> and <u>bumps on a second portion of the first surface, the spiral protrusions and bumps corresponding to original laser cuts</u>;

coating the first surface of the father stamper with nickel;

separating the nickel from the first surface to produce a second stamper having groove recesses <u>and pits</u> on a first surface, wherein the groove recesses are mirror images of the spiral protrusions <u>and the pits are mirror images of the bumps</u>;

covering the first surface of the second stamper with a plastic material; separating the plastic material from the second stamper, wherein the plastic material has lands corresponding to the groove recesses of the second stamper and bumps corresponding to the pits;

depositing a phase-change material directly over the lands <u>and bumps</u>, wherein the phase-change material is in a first state upon deposition and in a second state after being written to, and wherein the change from the first state to the second state changes the optical phase of the phase-change material in the positive direction, the lands forming a writeable area of the first-surface disk and the bumps forming a read-only area of the first-surface disk; and

depositing a dielectric layer over the phase-change material to form the first-surface optical disk, the dielectric layer being deposited to have a thickness that enhances an optical phase difference between the first and second states of the phase-change material, the first-surface optical disk consisting of no further layers.

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- (Original) The method of claim 1, wherein the covering comprises injecting the plastic material using an injection molding process.
- (Original) The method of claim 1, wherein the phase-change material is an SbInSn alloy.
- 4. (Original) The method of claim 1, wherein the providing comprises: providing a glass master disk with a first and a second principle surface; depositing a photoresist layer on the first principle surface of the disk; removing selected portions of the photoresist layer; depositing nickel over the photoresist layer; and separating the nickel from the photoresist layer to form the father stamper.
- 5. (Original) The method of claim 4, wherein the removing is by laser ablation
- (Original) The method of claim 4, wherein the removing comprises: exposing the selected portions of the photoresist layer; and etching the selected portions.
- 7. (Original) The method of claim 6, wherein the exposing is performed with a laser and results in the original laser cuts in the photoresist layer.
- 8. (Original) The method of claim 1, wherein data is written to the lands from exposure by a light source.
- (Original) The method of claim 4, further comprising rotating the glass master disk and exposing the selected portions with a laser prior to the etching.
- 10. (Original) The method of claim 4, wherein the deposited photoresist layer is between approximately 20 nm and 120 nm.

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- 11. (Original) The method of claim 4, wherein the deposited photoresist layer is between approximately 80 and 90 nm.
- 12. (Cancelled)
- (currently amended) The method of claim 1 42, wherein the dielectric layer comprises silicon oxynitride.
- 14. (cancelled)
- 15. (Original) The method of claim 1, wherein the second stamper is a mother stamper.
- 16. (Original) The method of claim 1, wherein the father stamper is a first generation stamper, and the second stamper is an even-numbered generation stamper.
- 17. (Original) The method of claim 1, wherein the second stamper has features that are opposite in polarity to features of the father stamper.
- 18. (Original) The method of claim 1, wherein the plastic material is a polycarbonate material.
- (currently amended) A method of forming a first-surface optical disk, comprising:

providing a stamper, wherein the stamper has grooves <u>and pits</u> corresponding to an original laser cut;

filling the grooves and pits with a plastic material;

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separating the plastic material from the stamper, wherein the plastic material has lands corresponding to the grooves and bumps corresponding to the pits;

depositing a phase-change material directly over the lands and bumps, wherein the phase-change material has a positive optical phase shift at portions that are written to, wherein the shift is caused by a physical change in the material and a change in optical constants of the material, the lands forming a writeable area of the first-surface disk and the bumps forming a read-only area of the first-surface disk, and

depositing a dielectric layer over the phase-change material to form the first-surface optical disk, the dielectric layer being deposited to have a thickness that enhances a contrast an optical phase change between an unwritten state and a written state of the phase-change material, the first-surface optical disk consisting of no further layers.

- The method of claim 19, wherein the phase-change material 20. (Original) comprises a SbInSn alloy.
- The method of claim 19, wherein data is written on the lands. 21. (Original)
- The method of claim 21, wherein the data is read by tracking 22. (Original) along the lands.
- 23. (Original) The method of claim 19, wherein the bumps are between approximately 80 nm and 90 nm in height.
- 24. (cancelled)
- The method of claim 19, wherein the stamper is a mother (Original) 25. stamper.

- 26. (Original) The method of claim 19, wherein the plastic material is a polycarbonate material.
- 27. (Cancelled)
- 28. (Cancelled)
- 29. (Cancelled)
- 30. (Cancelled).
- 31. (Cancelled)